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Information Disclosure Statement by Applicant						Applicant: Arman Sagatelian			
(Use several sheets if necessary)						Filed: January 22, 2002 Group: 2171			
U.S. Patent Documents									
Init.		Document No.	Date	Name	Class	Subclass	Filing Date		
ADM	1	5,475,695	12/12/1995	Caywood et al.	371	27	03/19/1993		
Foreign Documents									
								Translation	
Init.		Document No.	Date	Country	Class	Subclass	Yes	No	
Other Documents (Including Author, Title, Date, Pertinent Pages, etc.)									
ADM	2	K. Tobin, "Automated Analysis for Rapid Defect Sourcing and Yield Learning", <u>Future Fab International</u> , 15 pages, Vol. 4, 1997 (no month).							
ADM	3	"Semiconductor Spatial Signature Analysis (SSA)", [Internet] http://www-ismv.icornl.gov/projects/SSA.html , 6 pages, Revised March 31, 1999, printed 2/27/03							
ADM	4	J. Segal et al., "The Value of Electrical Bitmap Results from Embedded Memory Arrays for Rapid Yield Learning", <u>Digest of Papers, 2nd IEEE Latin American Test Workshop LATW2001</u> , pp. 266-272, Feb. 2001.							
Examiner						Date Considered <u>6/30/04</u>			
Examiner: Initial if citation considered, whether or not citation is in conference with MPEP 609; Draw line through citation if not conformance and not considered. Include a copy of this form with the next communication to applicant.									